## **Supporting Information**

Development of molecular precursors for deposition of indium sulphide thin film electrodes for photoelectrochemical applications

## **CHN Analysis**

Precursor [In(S<sub>2</sub>CNCy<sub>2</sub>)<sub>3</sub>]•2Py(1)

Run Details					Results		Simplest Empirical Formula		
Run	Run #	Created On	Weight	Carbon	Hydrogen	Nitrogen	Carbon	Hydrogen	Nitrogen
DD4	90	2012-8-27 4:39 PM	1.495	56.73	7.831	6.329	10.453	17.194	1

Precursor  $[In(S_2CN(^{i}Pr)_2)_3] \bullet 1.5Py (2)$ 

Run Details					Results		Simplest Empirical Formula		
Run	Run #	Created On	Weight	Carbon	Hydrogen	Nitrogen	Carbon	Hydrogen	Nitrogen
AA2	8	2012-10-16 11:40 AM	1.57	43.722	6.688	7.941	6.421	11.703	1

Precursor [In(S<sub>2</sub>CPip)<sub>3</sub>]•0.5Py (3)

Run Details					Results		Simplest Empirical Formula		
Run	Run #	Created On	Weight	Carbon	Hydrogen	Nitrogen	Carbon	Hydrogen	Nitrogen
E10	74	2012-10-3 11:24 AM	1.585	37.708	5.057	7.407	5.937	9.487	1

## Precursor [In(S<sub>2</sub>CNBzMe)<sub>3</sub>] (4)

Run Details				Results			Simplest Empirical Formula		
Run	Run #	Created On	Weight	Carbon	Hydrogen	Nitrogen	Carbon	Hydrogen	Nitrogen
DB2	87	2012-7-10 12:29 PM	2.071	45.696	4.334	6.057	8.893	9.983	1



S.Fig. 1a: H-NMR of Precursor [In(S<sub>2</sub>CNCy<sub>2</sub>)<sub>3</sub>]•2Py(1)



S.Fig. 1b: H-NMR of Precursor [In(S<sub>2</sub>CNCy<sub>2</sub>)<sub>3</sub>]•2Py(1)



S.Fig. 1c: H-NMR of Precursor [In(S<sub>2</sub>CNCy<sub>2</sub>)<sub>3</sub>]•2Py(1)



**S.Fig. 2a:** H-NMR of Precursor  $[ln(S_2CN(^{i}Pr)_2)_3] \bullet 1.5py (2)$ 



**S.Fig. 2b:** H-NMR of Precursor  $[In(S_2CN(^{i}Pr)_2)_3] \bullet 1.5py (2)$ 



**S.Fig. 2c:** H-NMR of Precursor  $[In(S_2CN(^iPr)_2)_3] \bullet 1.5py (2)$ 



**S.Fig. 3a:** H-NMR of Precursor  $[ln(S_2C(Pip))_3] \bullet 0.5py$  (**3**).



**S.Fig. 3b:** H-NMR of Precursor  $[In(S_2C(Pip))_3] \bullet 0.5py$  (3).



S.Fig. 4a: H-NMR of Precursor [In(S<sub>2</sub>CNBzMe)<sub>3</sub>] (4)



S.Fig. 4b: H-NMR of Precursor [In(S<sub>2</sub>CNBzMe)<sub>3</sub>] (4)



S.Fig. 4c: H-NMR of Precursor [In(S<sub>2</sub>CNBzMe)<sub>3</sub>] (4)



S. Fig. 5a: TG/DTG curves presenting losses in weight against temperature for precursor
[In(S<sub>2</sub>CNCy<sub>2</sub>)<sub>3</sub>] •2py (1)







**S. Fig. 5c:** TG/DTG curves presenting losses in weight against temperature for precursor  $In(S_2CPip)_3]$ •0.5Py (**3**)



 $[In(S_2CNBzMe)_3] (4)$ 



**S. Fig. 6:** Comparisons of PXRD patterns of  $\beta$ -In<sub>2</sub>S<sub>3</sub> thin films deposited from precursor [In(S<sub>2</sub>CNCy<sub>2</sub>)<sub>3</sub>]•2py (**1**), [In(S<sub>2</sub>CN(<sup>i</sup>Pr)<sub>2</sub>)<sub>3</sub>]•1.5py (**2**), [In(S<sub>2</sub>CPip)<sub>3</sub>]•0.5py (**3**) and [In(S<sub>2</sub>CNBzMe)<sub>3</sub>] (**4**) at 350 and 400°C with the standard ICSD= [98-002-3844] file.



**S. Fig. 7**: EDX spectra of β-In<sub>2</sub>S<sub>3</sub> thin films deposited using precursors [In(S<sub>2</sub>CNCy<sub>2</sub>)<sub>3</sub>]•2py (1) at (a) 300 °C (b) 350 °C (c) 400 °C[In(S<sub>2</sub>CN(<sup>*i*</sup>Pr)<sub>2</sub>)<sub>3</sub>]•1.5py (2) at (d) 300 °C (e) 350 °C and (f) 400 °C; [In(S<sub>2</sub>CPip)<sub>3</sub>]•0.5py (3) at (g) 300 °C (h) 350 °C (i) 400 °C and [In(S<sub>2</sub>CNBzMe)<sub>3</sub>] (4) at (x) 300 °C (y) 350 °C and (z) 400 °C.